WHAT IS CLAIMED IS

1. An alignment apparatus for aligning the central position and an orientation mark of a generally plate-like work with a predetermined position, comprising:

a table, which is provided rotatably in a plane and equipped with a loading plane having suction holes for said work, a shift mechanism for shifting the table, and a sensor, which is disposed adjacent to the outer edge portion of said work, for detecting the position of the outer edge and outputting detected positional data for shifting said table to a predetermined position, wherein

said loading plane is formed into a size so as to be positioned inside the periphery of said work; a receiving member is provided outside said table and is positioned on the generally same plane as said loading plane; and the periphery of the receiving member has a plane configuration so as to come to a position further outside the periphery of the work.

2. The alignment apparatus according to claim 1, wherein said sensor includes a light receiving element and a light emitting element disposed so as to optically sandwich the periphery portion of the work, and

said receiving member is formed using material having translucency.

3. The alignment apparatus according to claim 2, wherein said light emitting element comprises a receiving member of glass-like scatterer, and is formed so as to reflect

and project the light by allowing the light to enter the receiving member laterally.

4. The alignment apparatus according to claim 1, 2 or 3, wherein said receiving member is detachably attached around the periphery of the table.

5. An alignment apparatus for aligning the central position and an orientation mark of a generally plate-like work with a predetermined position, comprising:

a table, which is provided rotatably in a plane and equipped with a loading plane having suction holes for said work, a shift mechanism for shifting the table, and a sensor, which is disposed adjacent to the outer edge portion of said work, for detecting the position of the outer edge and outputting detected positional data for shifting said table to a predetermined position, wherein

said table is formed out of material having translucency, and is formed into a size so that the periphery edge thereof comes to a position further outside the periphery of said work.

6. The alignment apparatus according to any of claims 1-5, wherein said work comprises an ultrathin semiconductor wafer.